APPLICATION DATA SHEET

Application Information

Application number::

Filing Date::

Application type:: Regular Subject Matter:: Utility

Title line one::

Title line two::

Title line three::

LSI INSPECTION METHOD AND
DEFECT INSPECTION DATA
ANALYSIS APPARATUS

Attorney Docket Number:: 037133.53131US

Request for Early Publication?::

Request for Non-Publication?::

No
Suggested Drawing Figure::

Total Drawing Sheets::

Small Entity?::

Petition included?::

No

Petition Type::

Applicant Information

Applicant Authority Type:: Inventor Primary Citizenship:: Japanese Country:: Japan

Status:: Full Capacity

Given Name:: Yoji
Family Name:: Hata
Country of Residence:: Japan

Street of mailing address:: c/o UMC Japan

1580 Yamamoto Tateyama City

City of mailing address:: State or Province of

Mailing address:: Chiba

Country of mailing

address:: Japan

Postal or Zip Code

of mailing address:: 294-8502

Correspondence Information

Correspondence Customer

Number::

PATENT TRADEMARK OFFICE

Representative Information

Representative customer number::

PATENT TRADEMARK OFFICE

Domestic Priority Information

Application::	Continuity Type::	Parent Application::	Parent Filing Date::

Foreign Priority Information

Country::	Application number::	Filing Date::	Priority Claimed::
JP	106271/2003	April 10, 2003	Yes

Assignee Information

Assignee Name::

UMC Japan

Street of mailing address::

1580 Yamamoto

City of mailing address::

Tateyama City

State or Province of

Chiba

Mailing address:: Country of mailing

Japan

address::

Postal or Zip Code

294-8502

of mailing address::